Overview
Odyssey satisfies the requirements of today’s modern semiconductor fabs. Odyssey Defect is a production-proven defect data management solution that delivers real-time lot dispositioning, SPC alarming and a complete set of defect analysis tools to help fab engineers resolve both random and systematic yield issues.

Odyssey Defect has an open and vendor-neutral architecture that supports all inspection, review and classification tools with a full range of interactive charting, wafer mapping and reporting capabilities. A true 24x7 system, Odyssey Defect delivers results efficiently and reliably, leveraging error-correcting processes to assure users of maximum up time.

Benefits
• Easy to use Odyssey GUI enables high productivity
• Supports wide range of inspection and review tools. Automates in-line defect analysis to reduce diagnosis cycle time
• Real time server-based defect source analysis (DSA), SPC functions and automatic wafer sampling productivity through automated analysis
• Interactive spreadsheets and maps to arrive at root cause in minimal time
• High reliability with low maintenance, suitable for 24x7 fab operations
• Integrated automation features allow users to collaborate faster and address root cause analysis in minutes

Odyssey Yield Management Solution
Odyssey YMS is a complete yield management solution which combines the following modules and allows correlation between them.

• Defect
• Bin Sort
• Bit Fail (memory)
• Metrology
• Parametric
• WIP (MES)
Additional Modules

Additional modules integrate and manage critical manufacturing data to improve yields. These are:

- StatTool (statistical analysis and charting package)
- Real-time Kill Ratio engine (populates database at load time)

Figure 1: Odyssey’s interactive user interface and easy to create correlation plots across modules

Figure 2: StatTool performs multi-parameter correlation analysis to identify yield limiters